

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Masahiko NAKAMORI, et al.
Appl. No. : 10/536,621
Filed : May 26, 2005
For : POLISHING PAD AND METHOD
OF PRODUCING
SEMICONDUCTOR DEVICE
Examiner : Sylvia McCarthur
Group Art Unit : 1763

CERTIFICATE OF EFS WEB
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I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Time zone to the Commissioner for Patents via the EFS Web server on:

September 7, 2007

(Date)



Katsuhiro Arai, Reg. 43,315

RESPONSE TO ELECTION/RESTRICTIONS

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

This is in response to the Office communication from the Examiner mailed August 10, 2007.

Remarks begin on page 2 of this paper.